Table 4 to Subpart VVVVV of Part 63—Emission Limits and Compliance Requirements for Metal HAP Process Vents

As required in §63.11496(f), you must comply with the requirements for metal HAP process vents as shown in the following table.

<table>
<thead>
<tr>
<th>For * * *</th>
<th>You must * * *</th>
<th>Except * * *</th>
</tr>
</thead>
<tbody>
<tr>
<td>Each CMPU with total metal HAP emissions ≥400 lb/yr.</td>
<td>Reduce collective uncontrolled emissions of total metal HAP emissions by ≥95 percent by weight by routing emissions from a sufficient number of the metal process vents through a closed-vent system to any combination of control devices, according to the requirements of §63.11496(b)(3), (4), or (5).</td>
<td>Not applicable.</td>
</tr>
</tbody>
</table>

Table 5 to Subpart VVVVV of Part 63—Emission Limits and Compliance Requirements for Storage Tanks

As required in §63.11497, you must comply with the requirements for storage tanks as shown in the following table.

<table>
<thead>
<tr>
<th>For each * * *</th>
<th>You must * * *</th>
<th>Except * * *</th>
</tr>
</thead>
<tbody>
<tr>
<td>1. Storage tank with a design capacity ≥40,000 gallons, storing liquid that contains organic HAP listed in Table 1 to this subpart, and for which the maximum true vapor pressure (MTVP) of total organic HAP at the storage temperature is ≥5.2 kPa and &lt;76.6 kPa.</td>
<td>a. Comply with the requirements of subpart WW of this part;</td>
<td>i. All required seals must be installed by the compliance date in §63.11484.</td>
</tr>
<tr>
<td></td>
<td>b. Reduce total organic HAP emissions by ≥95 percent by weight by operating and maintaining a closed-vent system and control device (other than a flare) in accordance with §63.982(c)(1); or</td>
<td>i. Compliance may be based on either total organic HAP or TOC; ii. Comply with the management practice inspection requirements in §63.11496 for the closed-vent system; iii. When the term storage tank, surge control vessel, or bottoms receiver, as defined in §63.11502 of this subpart, applies; and iv. The requirements do not apply during periods of planned routine maintenance of the control device, as specified in §63.11497(b).</td>
</tr>
<tr>
<td></td>
<td>c. Reduce total HAP emissions by operating and maintaining a closed-vent system and a flare in accordance with §63.982(b); or</td>
<td>i. The requirements do not apply during periods of planned routine maintenance of the flare, as specified in §63.11497(b); and ii. When the term storage vessel is used in subpart SS of this part, it means storage tank, surge control vessel, or bottoms receiver, as defined in §63.11502 of this subpart.</td>
</tr>
<tr>
<td></td>
<td>d. Vapor balance in accordance with §63.2470(e); or</td>
<td>i. Not applicable.</td>
</tr>
<tr>
<td></td>
<td>e. Route emissions to a fuel gas system or process in accordance with the requirements in §63.982(d) and the requirements referenced therein.</td>
<td>i. When the term storage vessel is used in subpart SS of this part, it means storage tank, surge control vessel, or bottoms receiver, as defined in §63.11502.</td>
</tr>
</tbody>
</table>
For each * * * You must * * * Except * * *

2. Storage tank with a design capacity ≥20,000 gallons and <40,000 gallons, storing liquid that contains organic HAP listed in Table 1 to this subpart, and for which the MTVP of total organic HAP at the storage temperature is ≥27.6 kPa and <76.6 kPa.

   a. Comply with one of the options in Item 1 of this table.

   i. The information specified above for Items 1.a., 1.b., 1.c., 1.d, and 1.e, as applicable.

3. Storage tank with a design capacity ≥20,000 gallons, storing liquid that contains organic HAP listed in Table 1 to this subpart, and for which the MTVP of total organic HAP at the storage temperature is ≥76.6 kPa.

   a. Comply with option b, c, d, or e in Item 1 of this table.

   i. The information specified above for Items 1.b., 1.c., 1.d, and 1.e, as applicable.

4. Storage tank described by Item 1, 2, or 3 in this table and emitting a halogenated vent stream that is controlled with a combustion device.

   a. Reduce emissions of hydrogen halide and halogen HAP by ≥95 percent by weight, or to ≤0.45 kg/hr, or to ≤20 ppmv by using a halogen reduction device after the combustion device according to the requirements in §63.11496(d); or

   b. Reduce the halogen atom mass emission rate to ≤0.45 kg/hr or to ≤20 ppmv by using a halogen reduction device before the combustion device according to the requirements in §63.11496(d).

TABLE 6 TO SUBPART VVVVVV OF PART 63—EMISSION LIMITS AND COMPLIANCE REQUIREMENTS FOR WASTEWATER SYSTEMS

As required in §63.11498, you must comply with the requirements for wastewater systems as shown in the following table.

For each * * * You must * * * And you must * * *

1. Wastewater stream 

   a. Discharge to onsite or offsite treatment.

   i. Maintain records identifying each wastewater stream and documenting the type of treatment that it receives. Multiple wastewater streams with similar characteristics and from the same type of activity in a CMPU may be grouped together for recordkeeping purposes.

   ii. For the water phase, comply with the requirements in Item 1 of this table, and

   iii. For the organic phase(s), recycle to a process, use as fuel, or dispose as hazardous waste either onsite or offsite, and

   iv. Keep records of the wastewater streams subject to this requirement and the disposition of the organic phase(s).

2. Wastewater stream containing partially soluble HAP at a concentration ≥10,000 ppmv and separate organic and water phases.

   a. Use a decanter, steam stripper, thin film evaporator, or distillation unit to separate the water phase from the organic phase(s); or

   b. Hard pipe the entire wastewater stream to onsite treatment as a hazardous waste, or hard pipe the entire wastewater stream to a point of transfer for offsite treatment as a hazardous waste.

   i. For the water phase, comply with the requirements in Item 1 of this table, and

   ii. For the organic phase(s), recycle to a process, use as fuel, or dispose as hazardous waste either onsite or offsite, and

   iii. Keep records of the wastewater streams subject to this requirement and the disposition of the organic phase(s).

   iv. Keep records of the wastewater streams subject to this requirement and the disposition of the wastewater streams.